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<u>L8</u>	L7 and "FTIR".clm.	3	<u>L8</u>
<u>L7</u>	"alumina".clm.	38588	<u>L7</u>
<u>L6</u>	"alumina".clms.	0	<u>L6</u>
<u>L5</u>	alumina.clms.	0	<u>L5</u>
<u>L4</u>	(alumina same FTIR).clms.	0	<u>L4</u>
<u>L3</u>	(alumina same FTIR).clm.	0	<u>L3</u>
<u>L2</u>	(alumina same FTIR same adsorp\$)	3	<u>L2</u>
<u>L1</u>	(alumina same FTIR same band)	7	<u>L1</u>

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Day : Tuesday
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PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = CALLEGARI

First Name = ALESSANDRO

Application#	Patent#	Status	Date Filed	Title	Inventor Name
08664729	Not Issued	161	06/17/1996	CHEMICALLY AND OPTICALLY STABLE CARBON FILMS	CALLEGARI, ALESSANDRO
09067439	6448655	150	04/28/1998	STABILIZATION OF FLUORINE-CONTAINING LOW-K DIELECTRICS IN A METAL/INSULATOR WIRING STRUCTURE BY ULTRAVIOLET IRRADIATION	CALLEGARI, ALESSANDRO
10205526	6759321	150	07/25/2002	STABILIZATION OF FLUORINE-CONTAINING LOW-K DIELECTRICS IN A METAL/INSULATOR WIRING STRUCTURE BY ULTRAVIOLET IRRADIATION	CALLEGARI, ALESSANDRO
10630969	Not Issued	71	07/31/2003	Formation of ultra-thin oxide layers by self-limiting interfacial oxidation	CALLEGARI, ALESSANDRO
10630970	Not Issued	61	07/31/2003	Method of forming uniform ultra-thin oxynitride layers	CALLEGARI, ALESSANDRO
10662875	Not Issued	93	09/16/2003	INTERFACIAL OXIDATION PROCESS FOR HIGH-K GATE DIELECTRIC PROCESS INTEGRATION	CALLEGARI, ALESSANDRO
09676882	6664186	150	09/29/2000	METHOD OF FILM DEPOSITION, AND FABRICATION OF STRUCTURES	CALLEGARI, ALESSANDRO C.
09726951	6665033	150	11/30/2000	METHOD FOR FORMING ALIGNMENT LAYER BY ION BEAM SURFACE MODIFICATION.	CALLEGARI, ALESSANDRO C.

<u>09833550</u>	<u>6573197</u>	150	04/12/2001	THERMALLY STABLE POLY-SI/HIGH DIELECTRIC CONSTANT MATERIAL INTERFACES	CALLEGARI, ALESSANDRO C.
<u>09883578</u>	<u>6583847</u>	150	06/18/2001	SELF ALIGNMENT OF SUBSTRATES BY MAGNETIC ALIGNMENT	CALLEGARI, ALESSANDRO C.
<u>09888777</u>	<u>6511876</u>	150	06/25/2001	HIGH MOBILITY FETS USING AL2O3 AS A GATE OXIDE	CALLEGARI, ALESSANDRO C.
<u>09995031</u>	Not Issued	61	11/29/2001	High temperature processing compatible metal gate electrode for pFETS and methods for fabrication	CALLEGARI, ALESSANDRO C.
<u>10291334</u>	Not Issued	93	11/08/2002	DEPOSITION OF HAFNIUM OXIDE AND/OR ZIRCONIUM OXIDE AND FABRICATION OF PASSIVATED ELECTRONIC STRUCTURES	CALLEGARI, ALESSANDRO C.
<u>10606523</u>	Not Issued	71	06/26/2003	Stability of ion beam generated alignment layers by surface modification	CALLEGARI, ALESSANDRO C.
<u>10674961</u>	Not Issued	71	09/30/2003	Method of film deposition, and fabrication of structures	CALLEGARI, ALESSANDRO C.
<u>10712575</u>	Not Issued	61	11/13/2003	CVD tantalum compounds for FET gate electrodes	CALLEGARI, ALESSANDRO C.
<u>10873733</u>	Not Issued	30	06/22/2004	Method of forming metal/high-k gate stacks with high mobility	CALLEGARI, ALESSANDRO C.
<u>10923247</u>	Not Issued	30	08/20/2004	DUV laser annealing and stabilization of SiCOH films	CALLEGARI, ALESSANDRO C.
<u>11034597</u>	Not Issued	30	01/13/2005	TiC as a thermally stable p-metal carbide on high k SiO2 gate stacks	CALLEGARI, ALESSANDRO C.
<u>11035369</u>	Not Issued	30	01/13/2005	Method of forming HfSiN metal for n-FET applications	CALLEGARI, ALESSANDRO C.
<u>11180384</u>	Not Issued	20	07/13/2005	CVD tantalum compounds for FET gate electrodes	CALLEGARI, ALESSANDRO C.
<u>07140072</u>	<u>4853346</u>	150	12/31/1987	OHMIC CONTACTS FOR SEMICONDUCTOR DEVICES AND METHOD FOR FORMING OHMIC CONTACTS	CALLEGARI, ALESSANDRO C.
<u>07221686</u>	<u>4859253</u>	150	07/20/1988	METHOD FOR PASSIVATING A COMPOUND SEMICONDUCTOR SURFACE AND DEVICE HAVING	CALLEGARI, ALESSANDRO C.

				IMPROVED SEMICONDUCTOR- INSULATOR INTERFACE	
<u>08001374</u>	<u>5470661</u>	150	01/07/1993	DIAMOND-LIKE CARBON FILMS FROM A HYDROCARBON HELIUM PLASMA	CALLEGARI, ALESSANDRO C.
<u>08378848</u>	Not Issued	166	01/26/1995	SPUTTER DEPOSITION OF HYDROGENATED AMORPHOUS CARBON FILM AND APPLICATIONS THEREOF	CALLEGARI, ALESSANDRO C.
<u>08483685</u>	<u>5569501</u>	150	06/07/1995	DIAMOND-LIKE CARBON FILMS FROM A HYDROCARBON HELIUM PLASMA	CALLEGARI, ALESSANDRO C.
<u>08781080</u>	<u>5830332</u>	150	01/09/1997	SPUTTER DEPOSITION OF HYDROGENATED AMORPHOUS CARBON FILM AND APPLICATIONS THEREOF	CALLEGARI, ALESSANDRO C.
<u>09112919</u>	<u>6184121</u>	150	07/09/1998	CHIP INTERCONNECT WIRING STRUCTURE WITH LOW DIELECTRIC CONSTANT INSULATOR AND METHODS FOR FABRICATING THE SAME	CALLEGARI, ALESSANDRO C.
<u>09139367</u>	Not Issued	161	08/25/1998	LITHOGRAPHIC STRUCTURES HAVING INDEX OF REFRACTION AND EXTINCTION COEFFICIENTS PROFILES FOR CONTROLLING REFLECTION TO CONTROL UNEWIDTH VARIATION	CALLEGARI, ALESSANDRO C.
<u>09455671</u>	<u>6682786</u>	150	12/07/1999	LIQUID CRYSTAL DISPLAY CELL HAVING LIQUID CRYSTAL MOLECULES IN VERTICAL OR SUBSTANTIALLY VERTICAL ALIGNMENT	CALLEGARI, ALESSANDRO C.
<u>60052174</u>	Not Issued	159	07/10/1997	CHIP INTERCONNECT WIRING STRUCTURE WITH LOW DIELECTRIC CONSTANT INSULATOR AND METHODS FOR FABRICATING THE SAME	CALLEGARI, ALESSANDRO C.

<u>09597780</u>	Not Issued	71	06/20/2000	Multi-domain and IPS liquid-crystal display using dry alignment	CALLEGARI, ALESSANDRO CESARE
<u>09619512</u>	<u>6413386</u>	150	07/19/2000	REACTIVE SPUTTERING METHOD FOR FORMING METAL-SILICON LAYER	CALLEGARI, ALESSANDRO CESARE
<u>09694173</u>	<u>6395650</u>	150	10/23/2000	METHODS FOR FORMING METAL OXIDE LAYERS WITH ENHANCED PURITY	CALLEGARI, ALESSANDRO CESARE
<u>09715559</u>	<u>6577011</u>	150	11/17/2000	CHIP INTERCONNECT WIRING STRUCTURE WITH LOW DIELECTRIC CONSTANT INSULATOR AND METHODS FOR FABRICATING THE SAME	CALLEGARI, ALESSANDRO CESARE
<u>09740721</u>	Not Issued	163	12/18/2000	Low temperature thin film transistor fabrication	CALLEGARI, ALESSANDRO CESARE
<u>10099004</u>	<u>6770500</u>	150	03/15/2002	PROCESS OF PASSIVATING A METAL-GATED COMPLEMENTARY METAL OXIDE SEMICONDUCTOR	CALLEGARI, ALESSANDRO CESARE
<u>10660364</u>	Not Issued	30	09/11/2003	Ion gun deposition and alignment for liquid-crystal applications	CALLEGARI, ALESSANDRO CESARE
<u>10689222</u>	Not Issued	71	10/20/2003	Germanate gate dielectrics for semiconductor devices	CALLEGARI, ALESSANDRO CESARE
<u>08868772</u>	<u>6428894</u>	150	06/04/1997	TUNABLE AND REMOVABLE PLASMA DEPOSITED ANTIREFLECTIVE COATINGS	CALLEGARI, ALESSANDRO CESARE
<u>08924476</u>	Not Issued	161	08/25/1997	LAYERED RESIST SYSTEM USING TUNABLE AMORPHOUS CARBON FILM AS A BOTTOM LAYER AND METHODS OF FABRICATION THEREOF	CALLEGARI, ALESSANDRO CESARE
<u>09020308</u>	Not Issued	161	02/06/1998	HIGH RESOLUTION DUV PHOTOMASKS USING A CONDUCTIVE TRANSFER LAYER AND METHODS OF FABRICATION THEREOF	CALLEGARI, ALESSANDRO CESARE
<u>09027997</u>	<u>6061114</u>	150	02/23/1998	ALIGNMENT OF LIQUID CRYSTAL LAYERS	CALLEGARI, ALESSANDRO

					CESARE
09028018	6020946	150	02/23/1998	DRY PROCESSING FOR LIQUID-CRYSTAL DISPLAYS USING LOW ENERGY ION BOMBARDMENT	CALLEGARI, ALESSANDRO CESARE

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PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = NEUMAYER

First Name = DEBORAH

Application#	Patent#	Status	Date Filed	Title	Inventor Name
07530713	Not Issued	161	05/30/1990	WATER RESISTANT VERMICULITE ARTICLES AND METHOD OF THEIR MANUFACTURE	NEUMAYER, DEBORAH
07530714	5244740	150	05/30/1990	WATER RESISTANT/REPELLANT VERMICULITE ARTICLES AND METHOD OF THEIR MANUFACTURE	NEUMAYER, DEBORAH
07530715	5330843	150	05/30/1990	WATER RESISTANT VERMICULITE ARTICLES AND METHOD OF THEIR MANUFACTURE	NEUMAYER, DEBORAH
10689675	Not Issued	30	10/22/2003	Control of carbon nanotube diameter using CVD or PECVD growth	NEUMAYER, DEBORAH
10838849	Not Issued	71	05/03/2004	Method for fabricating an ultralow dielectric constant material as an intralevel or interlevel dielectric in a semiconductor device and electronic device made	NEUMAYER, DEBORAH
09592031	Not Issued	161	06/12/2000	CMOS metal high-K gate device and method of fabrication	NEUMAYER, DEBORAH A.
09924548	6541331	150	08/09/2001	METHOD OF MANUFACTURING HIGH DIELECTRIC CONSTANT MATERIAL	NEUMAYER, DEBORAH A.
10291334	Not Issued	93	11/08/2002	DEPOSITION OF HAFNIUM OXIDE AND/OR ZIRCONIUM OXIDE AND FABRICATION OF PASSIVATED ELECTRONIC STRUCTURES	NEUMAYER, DEBORAH A.
10305767	6888714	150	11/27/2002	TUNEABLE FERROELECTRIC DECOUPLING CAPACITOR	NEUMAYER, DEBORAH A.
10338481	6653246	150	01/08/2003	HIGH DIELECTRIC CONSTANT MATERIALS	NEUMAYER, DEBORAH A.
10964254	Not	30	10/13/2004	Ultra low k plasma enhanced chemical	NEUMAYER,

	Issued			vapor deposition processes using a single bifunctional precursor containing both a SiCOH matrix functionality and organic porogen functionality	DEBORAH A.
<u>11040778</u>	Not Issued	20	01/21/2005	SiCOH dielectric material with improved toughness and improved Si-C bonding, semiconductor device containing the same, and method to make the same	NEUMAYER, DEBORAH A.
<u>11132108</u>	Not Issued	30	05/18/2005	SiCOH dielectric material with improved toughness and improved Si-C bonding, semiconductor device containing the same, and method to make the same	NEUMAYER, DEBORAH A.
<u>11190360</u>	Not Issued	20	07/27/2005	Materials containing voids with void size controlled on the nanometer scale	NEUMAYER, DEBORAH A.
<u>08520680</u>	<u>5675028</u>	250	08/29/1995	BISAMIDO AZIDES OF GALLIUM, ALUMINUM AND INDIUM AND THEIR USE AS PRECURSORS FOR THE GROWTH OF NITRIDE FILMS	NEUMAYER, DEBORAH A.
<u>09378502</u>	Not Issued	94	08/20/1999	DELIVERY SYSTEMS FOR GASES FOR GASES VIA THE SUBLIMATION OF SOLID PRECURSORS	NEUMAYER, DEBORAH A.
<u>09430901</u>	<u>6507476</u>	150	11/01/1999	TUNEABLE FERROELECTRIC DECOUPLING CAPACITOR	NEUMAYER, DEBORAH A.
<u>09553997</u>	Not Issued	95	04/20/2000	PRECURSOR SOURCE MIXTURES	NEUMAYER, DEBORAH ANN
<u>09676882</u>	<u>6664186</u>	150	09/29/2000	METHOD OF FILM DEPOSITION, AND FABRICATION OF STRUCTURES	NEUMAYER, DEBORAH ANN
<u>09757154</u>	Not Issued	161	01/09/2001	BEOL decoupling capacitor	NEUMAYER, DEBORAH ANN
<u>09841947</u>	Not Issued	161	04/25/2001	Amorphous dielectric capacitors on silicon	NEUMAYER, DEBORAH ANN
<u>09841948</u>	Not Issued	161	04/25/2001	Amorphous dielectric capacitors on silicon	NEUMAYER, DEBORAH ANN
<u>09888777</u>	<u>6511876</u>	150	06/25/2001	HIGH MOBILITY FETS USING AL ₂ O ₃ AS A GATE OXIDE	NEUMAYER, DEBORAH ANN
<u>09924660</u>	<u>6555859</u>	150	08/08/2001	FLIP FERAM CELL AND METHOD TO FORM SAME	NEUMAYER, DEBORAH ANN

<u>09927694</u>	<u>6773982</u>	150	08/10/2001	FERAM CELL WITH INTERNAL OXYGEN SOURCE AND METHOD OF OXYGEN RELEASE	NEUMAYER, DEBORAH ANN
<u>10055704</u>	<u>6525427</u>	150	01/22/2002	BEOL DECOUPLING CAPACITOR	NEUMAYER, DEBORAH ANN
<u>10320185</u>	Not Issued	161	12/16/2002	Beol decoupling capacitor	NEUMAYER, DEBORAH ANN
<u>10323132</u>	<u>6777809</u>	150	12/19/2002	BEOL DECOUPLING CAPACITOR	NEUMAYER, DEBORAH ANN
<u>10384002</u>	Not Issued	61	03/07/2003	Flip feram cell and method to form same	NEUMAYER, DEBORAH ANN
<u>10674961</u>	Not Issued	71	09/30/2003	Method of film deposition, and fabrication of structures	NEUMAYER, DEBORAH ANN
<u>10689222</u>	Not Issued	71	10/20/2003	Germanate gate dielectrics for semiconductor devices	NEUMAYER, DEBORAH ANN
<u>10830798</u>	Not Issued	71	04/23/2004	BEOL decoupling capacitor	NEUMAYER, DEBORAH ANN
<u>11034479</u>	Not Issued	30	01/13/2005	Ultralow dielectric constant layer with controlled biaxial stress	NEUMAYER, DEBORAH ANN
<u>08827015</u>	<u>5946551</u>	150	03/25/1997	FABRICATION OF THIN FILM EFFECT TRANSISTOR COMPRISING AN ORGANIC SEMICONDUCTOR AND CHEMICAL SOLUTION DEPOSITED METAL OXIDE GATE DIELECTRIC	NEUMAYER, DEBORAH ANN
<u>08827018</u>	<u>5981970</u>	150	03/25/1997	THIN-FILM FIELD-EFFECT TRANSISTOR WITH ORGANIC SEMICONDUCTOR REQUIRING LOW OPERATING VOLTAGES	NEUMAYER, DEBORAH ANN
<u>08964607</u>	Not Issued	161	11/05/1997	METHOD FOR FORMING NOBL METAL OXIDES AND STRUCTURES FORMED THEREOF	NEUMAYER, DEBORAH ANN
<u>09016793</u>	<u>5962654</u>	150	01/30/1998	NOVEL ALKOXYALKOXIDES AND USE TO FORM FILMS	NEUMAYER, DEBORAH ANN
<u>09148613</u>	<u>6002031</u>	150	09/04/1998	NOVEL METAL ALKOXYALKOXIDECARBOXYLATES AND USE TO FORM FILMS	NEUMAYER, DEBORAH ANN

09183413	6172385	150	10/30/1998	MULTILAYER FERROELECTRIC CAPACITOR STRUCTURE	NEUMAYER, DEBORAH ANN
09225526	Not Issued	161	01/04/1999	BEOL DECOUPLING CAPACITOR	NEUMAYER, DEBORAH ANN
09300185	6255122	150	04/27/1999	AMORPHOUS DIELECTRIC CAPACITORS ON SILICON	NEUMAYER, DEBORAH ANN
09323804	6344660	150	06/02/1999	THIN-FILM FIELD-EFFECT TRANSISTOR WITH ORGANIC SEMICONDUCTOR REQUIRING LOW OPERATING VOLTAGES	NEUMAYER, DEBORAH ANN
09325857	6388285	150	06/04/1999	FERAM CELL WITH INTERNAL OXYGEN SOURCE AND METHOD OF OXYGEN RELEASE	NEUMAYER, DEBORAH ANN
09326181	Not Issued	161	06/04/1999	DRAM AND FRAM CELLS CONTAINING DECOMPOSABLE METAL OXIDE ELECTRODES	NEUMAYER, DEBORAH ANN
09383744	6333202	150	08/26/1999	FLIP FERAM CELL AND METHOD TO FORM SAME	NEUMAYER, DEBORAH ANN
09421096	6203613	150	10/19/1999	ATOMIC LAYER DEPOSITION WITH NITRATE CONTAINING PRECURSORS	NEUMAYER, DEBORAH ANN

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